

Amendments to the Claims:

This listing of claims replaces all prior versions and listings of claims in the application:

Listing of Claims

Please cancel claims 1-26.

27. A method of fabricating micro-mirror structures in a micro-mirror strip of micro-mirror structures comprising:

forming a pyramidal structure from a substrate material; and  
defining electrodes on the pyramidal structure.

28. The method of 27, wherein forming the pyramidal structure comprises:  
anisotropic etching the pyramidal structure to form steps of various depths in the structure.

29. The method of claim 27, wherein the electrodes include four electrodes and forming the electrodes further comprises  
arranging each electrode on a different one of quadrants of the pyramidal structure.

30. The method of claim 28, wherein the steps are polygonal in shape.

31. The method of claim 27, wherein a second wafer is bonded to the processed wafer.

32. The method of claim 31, wherein the second wafer is a silicon-on-insulator wafer and is bonded to the wafer with a device side facing the wafer.

33. The method of claim 31, further comprising:  
disposing a material to define a mirror in a surface of the second wafer.

34. The method of claim 31, further comprising:  
defining sensors in the surface of the second wafer.

35. The method of claim 27, further comprising:  
adding dam structures to the wafer to isolate the structure from adjacent micro-mirror structures in a strip of micro-mirror structures.

36. The method of claim 34, further comprising:  
defining other electronic components of the micro-mirror structure in one or the other of the wafers.

37. A hinge comprising:  
a plurality of parallel hinge sections provided by vertical slots therein, the slots and parallel hinge sections being dimensioned to provide vertical and lateral stiffness to and a minimal torsion spring constant for the hinge.

38. A micro-mirror strip assembly comprising:  
a frame;  
an array of two-dimensional deflecting mirrors mounted in the frame; and  
dams disposed between the mirrors to block viscous interaction between each of the two dimensional deflecting mirrors and adjacent ones of the two-dimensional deflecting mirrors in the array.